

Postdoctoral Research Associate Position working on in-situ XPS metrology for plasma-based process monitoring

A postdoctoral research associate position for a highly motivated and experienced experimentalist **to develop and test the innovative in-situ XPS metrology for plasma-based process monitoring** is anticipated to be available starting in the Fall of 2025. This experimentalist position requires a deep knowledge of plasma-surface interactions and plasma chemistry relevant to semiconductor fabrication. Also required hands-on experience in the design & assembly of vacuum equipment and plasma sources, with plasma diagnostics (Langmuir, optical probes, electron/ion fluxes & energy distributions at the substrate level. The preferred candidate will have experience with XPS, AES, SEM sample characterization, semiconductor device fabrication processes, excellent writing, communication, and teamwork skills, etc. This is two years appointment with an annual pay above \$ 90,000 and will be located in Gaithersburg, MD, USA

Applicants should send a cover letter, CV, reprints of representative publications, and contact information for 3 references to Dr. Andrei Kolmakov, andrei.kolmakov@nist.gov, 301-974-4724.